

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	256585	(measur\$3 or test\$3) near7 (surface or workpiece)	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:03
L2	33550	(measur\$3 or test\$3) near9 interfer\$4	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 16:01
L3	1451	1 and 2 and ((first or second or main or primary) near4 (beam or emit\$4 or radiat\$3))	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:51
L4	10953	(reference near4 (test\$3 or measur\$3 or surface)) near9 (adjacent or next or relative)	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:06
L5	191	3 and 4	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:17
L6	119	5 and (beam adj splitter) and interference	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:14
L7	100	6 and ((test\$3 or measur\$3) near2 surface)	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:39
L8	29	7 and tube and (open\$3 or holes)	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:50
L9	6	8 and (plane near2 mirror)	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:42
L10	92	(measur\$3 or test\$3) near2 probe near2 interfer\$4	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:58
L11	1	1 and 10 and 4 and ((first or second or main or primary) near4 (beam or emit\$4 or radiat\$3))	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:51
L12	2	("5907400").PN.	USPAT; EPO; JPO; DERWENT	OR	OFF	2006/02/28 15:57
L13	0	4 and 12	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:58
L14	105109	(measur\$3 or test\$3) near4 (interfer\$4 or beam or radiat\$3)	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 16:02
L15	5447	(align\$3 or parallel\$3 or along) near7 ((measur\$3 or test) near2 surface)	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 16:03

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L16	297	14 near9 15	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 16:04
L17	55	3 and 16	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 16:04
L18	20	4 and 17	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 16:10

US 7006235 B2	Methods and systems 356/600	356/401; 356/601; 356/73
US 6950196 B2	Methods and systems 356/630	356/237.2; 356/369
US 6946394 B2	Methods and systems 438/680	356/237.2; 356/237.3; 356/600; 3
US 6919957 B2	Methods and systems 356/237.2	250/559.42; 257/E21.53; 356/237
US 6917433 B2	Methods and systems 356/630	257/E21.53; 324/229
US 6917419 B2	Methods and systems 356/237.2	250/559.42; 257/E21.53; 356/237
US 6906782 B2	Stage apparatus, scar 355/53	355/72; 355/76
US 6891627 B1	Methods and systems 356/625	257/E21.53; 356/237.2; 356/237.
US 6891610 B2	Methods and systems 356/237.2	257/E21.53; 356/237.3; 356/237.
US 6829559 B2	Methods and systems 702/155	257/E21.53; 702/35 CIPG 20060
US 6818459 B2	Methods and systems 438/14	257/E21.53; 356/72; 438/16
US 6812045 B1	Methods and systems 438/14	438/15
US 6806951 B2	Methods and systems 356/237.2	257/E21.53; 356/237.4
US 6782337 B2	Methods and systems 702/155	250/559.24; 250/559.42; 257/E21
US 6762844 B2	Optical microscope us 356/484	
US 6744518 B2	Interferometric source 356/450	356/484
US 6694284 B1	Methods and systems 702/155	702/35
US 6678054 B1	Quantum channel for 356/450	356/484
US 6673637 B2	Methods and systems 438/14	257/E21.53; 356/72
US 6633831 B2	Methods and systems 702/155	257/E21.53; 702/167
US 6515750 B1	Interferometric system 356/512	356/515
US 6331885 B1	Stage apparatus, scar 355/53	356/399; 356/400; 356/401; 356/
US 5991034 A	Interferometer which v 356/511	356/489
US 5446547 A	Combination of motori 356/511	
US 4900940 A	Optical system for me 250/559.23	356/602
US 4650335 A	Comparison type dime 356/398	356/369
US 3843261 A	METHOD AND APPA 356/505	
US 3840301 A	APPARATUS AND MI 356/505	356/511; 356/601
US 3597091 A	INTERFEROMETER 356/498	

US 6906782 B2	Stage apparatus, scar 355/53	355/72; 355/76
US 6331885 B1	Stage apparatus, scar 355/53	356/399; 356/400; 356/401; 356/402
US 5991034 A	Interferometer which v 356/511	356/489
US 3843261 A	METHOD AND APPARATUS	356/505
US 3840301 A	APPARATUS AND METHOD	356/511; 356/601
US 3597091 A	INTERFEROMETER	356/498

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US 6781699 B2	Two-wavelength conf	356/511	356/241.3
US 5907400 A	Folded low-power inte	356/511	359/370
US 6885459 B2	Apparatus and metho	356/503	356/512
US 6771735 B2	Method and apparatu	378/70	
US 6757067 B2	Fringe pattern discrim	356/504	356/512
US 6731388 B1	Method of measuring	356/445	
US 6492957 B2	Close-proximity radiat	343/841	250/336.1; 250/366; 324/95; 343/
US 6473185 B2	Alignment free interfer	356/512	356/514
US 6404502 B2	Dual standard gloss s	356/445	
US 6401349 B1	Surface measuring ap	33/551	33/549; 33/553
US 6344898 B1	Interferometric appar	356/513	356/521
US 6331885 B1	Stage apparatus, scar	355/53	356/399; 356/400; 356/401; 356/
US 6043886 A	Interferometric metho	356/481	
US 5995222 A	Subject positioning de	356/508	356/498; 356/512
US 5991035 A	Interferometric metho	356/512	
US 5923425 A	Grazing incidence inte	356/520	
US 5923174 A	Device for measuring	324/637	324/642
US 5909282 A	Interferometer for me	356/504	
US 5889591 A	Interferometric measu	356/512	
US 5886786 A	Subject positioning de	356/508	356/498; 356/512
US 5811793 A	Rain sensor for glass	250/227.2	250/216; 318/483
US 5793488 A	Interferometer with co	356/512	
US 5757493 A	Interferometer with ca	356/511	359/487; 359/727
US 5719676 A	Diffraction manage	356/512	
US 5710631 A	Apparatus and metho	356/495	356/516
US 5654798 A	Interferometric measu	356/512	356/521
US 5640270 A	Orthogonal-scanning	359/368	250/201.3; 250/559.22; 356/511;
US 5572032 A	Gas analyzer and gas	250/345	250/339.12; 250/339.13; 250/343
US 5563706 A	Interferometric surfac	356/495	356/513; 356/514
US 5523839 A	Differential optical inte	356/489	356/516
US 5514971 A	Method and apparatu	324/639	324/501; 324/537; 324/628; 324/
US 5488477 A	Methods and apparatu	356/514	
US 5469259 A	Inspection interferome	356/495	
US 5424828 A	Method for measuring	356/458	356/513; 359/15
US 5374991 A	Compact distance me	356/493	
US 5218425 A	Measuring method an	356/510	356/520
US 5076695 A	Interferometer	356/513	
US 5067817 A	Method and device fo	356/613	
US 5064286 A	Optical alignment sys	356/153	356/508
US 5061071 A	Method and apparatu	356/489	250/201.4; 356/495

US 5051575 A	Optical surface roughness	250/225	250/559.22; 356/369; 359/494; 359/500
US 4869593 A	Interferometric surface	356/495	
US 4732483 A	Interferometric surface	356/495	
US 4643517 A	Method and circuit arrangement	359/213	
US 4534649 A	Surface profile interferometer	356/495	
US 4509858 A	Compact, linear measurement	356/498	
US 4498771 A	Method and means for	356/495	
US 4427295 A	Measuring apparatus	356/613	356/369
US 4372680 A	Miniature spectrally selective	356/51	250/338.1; 250/474.1
US 4278933 A	Means and method for	324/627	324/632
US 4221486 A	Interferometric measurement	356/504	
US 4188124 A	Interferometric measurement	356/512	356/521
US 4046477 A	Interferometric method	356/35.5	356/502; 73/596; 73/643; 73/657
JP 09113237 A	FOLDED NULL INTERFEROMETER		
JP 03130603 A	INSPECTION OF MOLDING DIE 356/137		

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US 6781699 B2	Two-wavelength conf	356/511	356/241.3
US 6757067 B2	Fringe pattern discrim	356/504	356/512
US 6492957 B2	Close-proximity radiat	343/841	250/336.1; 250/366; 324/95; 343/
US 6331885 B1	Stage apparatus, scar	355/53	356/399; 356/400; 356/401; 356/
US 6043886 A	Interferometric metho	356/481	
US 5991035 A	Interferometric metho	356/512	
US 5889591 A	Interferometric measu	356/512	
US 5793488 A	Interferometer with co	356/512	
US 5757493 A	Interferometer with ca	356/511	359/487; 359/727
US 5640270 A	Orthogonal-scanning	359/368	250/201.3; 250/559.22; 356/511;
US 5488477 A	Methods and apparatu	356/514	
US 5424828 A	Method for measuring	356/458	356/513; 359/15
US 5374991 A	Compact distance me	356/493	
US 5076695 A	Interferometer	356/513	
US 5067817 A	Method and device fo	356/613	
US 5061071 A	Method and apparatu	356/489	250/201.4; 356/495
US 5051575 A	Optical surface rough	250/225	250/559.22; 356/369; 359/494; 3
US 4869593 A	Interferometric surfac	356/495	
US 4498771 A	Method and means fo	356/495	
US 4046477 A	Interferometric metho	356/35.5	356/502; 73/596; 73/643; 73/657

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